



AF/1765
Gfw

Docket No. 56775 (70551)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: N. Kanetsuki, et al.

EXAMINER: L. Vinh

U.S.S.N.: 10/015,446

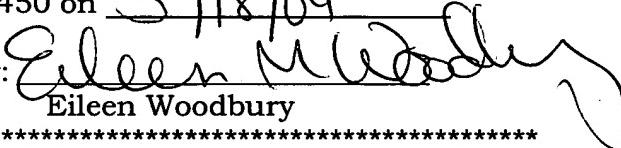
ART UNIT: 1765

FILED: 12/12/2001

FOR: Plasma Processing Method

CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5/18/04

By: 
Eileen Woodbury

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO FINAL OFFICE ACTION

The following is in response to the Office Action mailed February 24, 2004, in the above referenced application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.